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Docket No. 740107-135

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of)
Nobuo SHIMAZU et al.) : Group Art Unit: Unknown
Application No.: 09/732,927) : Examiner: Unknown
Filed: December 11, 2000)
For: MANUFACTURING METHOD OF MASK)
FOR ELECTRON BEAM PROXIMITY :
EXPOSURE AND MASK)

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
Washington, D.C. 20231

Sir:

In accordance with the duty of disclosure as set forth in 37 C.F.R. §1.56, Applicants hereby submit the following information in conformance with 37 C.F.R. §§ 1.97 and 1.98. Pursuant to 37 C.F.R. § 1.98, a copy of each of the documents cited is enclosed.

The references, which are listed on attached Form PTO-1449, are discussed in the specification.

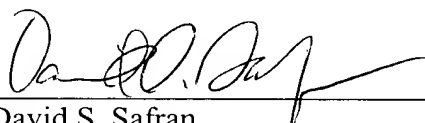
The documents are being submitted within 3 months of the filing, or entry into the national phase, of this application or before the first Office Action on the merits, whichever is later, therefore no fee or certification is required under 37 C.F.R. § 1.97(b).

To assist the Examiner, the documents are listed on the attached form PTO-1449. It is respectfully requested that an Examiner initialled copy of this form be returned to the undersigned.

Respectfully submitted,

Date: May 30, 2001

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